

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

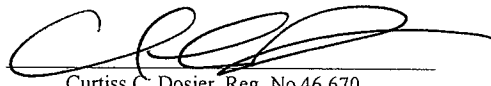
Applicant : Tetsuo SHIMOMURA et al.
App. No : 10/598,717
Filed : September 8, 2006
For : POLISHING PAD AND
SEMICONDUCTOR DEVICE
MANUFACTURING METHOD
Examiner : Alvin J Grant
Art Unit : 3723
Conf # : 9262

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I hereby certify that this correspondence, and any other attachment noted on the automated Acknowledgement Receipt, is being transmitted from within the Pacific Time zone to the Commissioner for Patents via the EFS Web server on:

July 11, 2008

(Date)


Curtiss C. Dosier, Reg. No.46,670AMENDMENT**Mail Stop Amendment**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed April 11th, 2008, please reconsider the present application in light of the following amendments and comments.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 9 of this paper.